

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant	:	Weeks et al.
Appl. No.	:	10/769,549
Filed	:	January 30, 2004
For	:	APPARATUS AND METHODS FOR PREVENTING ROTATIONAL SLIPPAGE BETWEEN A VERTICAL SHAFT AND A SUPPORT STRUCTURE FOR A SEMICONDUCTOR WAFER HOLDER
Examiner	:	Rakesh K. Dhingra
Group Art Unit	:	1763

COMMENTS ON EXAMINER'S STATEMENT ON REASONS FOR ALLOWANCE**Mail Stop Amendment**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Dear Sir:

This paper is responsive to the Notice of Allowability.

Remarks/Arguments begin on page 2 of this paper.

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REMARKS

In the Notice of Allowability, the Examiner states the following:

“The following is an examiner’s statement of reasons for allowance:

Claim 1: Prior art (US PG PUB No. 2003/0224104, Chondroudis et al) does not teach claim limitation inter alia, ‘a securing element that enables selective engagement/disengagement of the retaining member between the substrate holder support and the rotational drive’.”

Applicants respectfully submit that the claims are allowable as amended in the Amendment filed on June 26, 2006. Nonetheless, Applicants have agreed to the Examiner’s proposed amendment in order to expedite allowance of this application. Applicants reserve the right to pursue the claims as submitted in the Amendment filed on June 26, 2006 (or claims of similar scope), in a continuing application.

Please charge any additional fees, including any fees for additional extension of time, or credit overpayment to Deposit Account No. 11-1410.

Respectfully submitted,

KNOBBE, MARTENS, OLSON & BEAR, LLP

Dated: 12/19/06

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